

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

1. (currently amended) In a MEMS device, the improvement comprising:
a plurality of sensors electrically isolated from one another and positioned about an axis of symmetry to produce signals of substantially identical characteristics; and
circuitry responsive to said plurality of sensors for comparing said signals produced by said plurality of sensors to identify asymmetries in said MEMS device.
2. (original) The MEMS device of claim 1 additionally comprising circuitry for actuating the MEMS device.
3. (original) The MEMS device of claim 1 wherein said MEMS device is implemented using batch-fabrication techniques, and wherein said circuitry and connections between said circuitry and said sensors are implemented using batch-fabrication techniques.
4. (original) The MEMS device of claim 1 wherein said MEMS device is selected from the group consisting of resonators, accelerometers, gyroscopes, antennas, micromotors and ink jet print head microsystems.
5. (currently amended) A MEMS device, comprising:
a plurality of fixed beams arranged symmetrically;
a plurality of movable beams arranged symmetrically;
a first sensor formed by certain of said fixed and movable beams;
a second sensor, electrically isolated from said first sensor, and formed by at least certain other of said fixed and movable beams; and
a circuit responsive to said first and second sensors for comparing signals produced by said first and second sensors to identify asymmetries in said MEMS device.
6. (original) The device of claim 5 additionally comprising circuitry for actuating said plurality of movable beams.
7. (original) The device of claim 5 wherein said MEMS device is implemented using batch-fabrication techniques, said circuit and connections between said circuit and said sensors are implemented using batch-fabrication techniques.

8. (currently amended) In a symmetric MEMS device, the improvement comprising:
a plurality of sensors positioned about an axis of symmetry to produce signals of substantially identical characteristics; and

circuitry responsive to said plurality of sensors for real time comparison of said signals produced by said plurality of sensors.

9. (original) The MEMS device of claim 8 additionally comprising circuitry for actuating the MEMS device.

10. (original) The MEMS device of claim 8 wherein said MEMS device is implemented using batch-fabrication techniques, said circuitry and connections between said circuitry and said sensors are implemented using batch-fabrication techniques.

11. (original) The MEMS device of claim 8 wherein said MEMS device is selected from the group consisting of resonators, accelerometers, gyroscopes, antennas, micromotors and ink jet print head microsystems.

12. (original) A MEMS device, comprising:
a plurality of fixed beams arranged symmetrically;
a plurality of movable beams arranged symmetrically;
a first sensor formed by certain of said fixed and movable beams;
a second sensor formed by at least certain other of said fixed and movable beams; and
a circuit responsive to said first and second sensors for real time comparison of said signals produced by said sensors.

13. (original) The MEMS device of claim 12 additionally comprising circuitry for actuating said plurality of movable beams.

14. (original) The MEMS device of claim 12 wherein said MEMS device is implemented using batch-fabrication techniques, said circuit and connections between said circuit and said sensors are implemented using batch-fabrication techniques.

15 – 27. Canceled.